PDE Measurement of SiPMs

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Highly Granular Hadronic Calorimeter

CALICE: Calorimeter for the Linear Collider Experiment





Wavelength schifting fibre blue → green (highest sensitivity of sensor) + response uniformity

- Several producers/sensor types
- Which sensor ist best for the application?
- Characterisation is needed

Characterisation of SiPMs

- Test-setup for SiPM-measurements at KIP (Heidelberg)
 - Basic characterisation:
 - Dark-Rate
 - Crosstalk prob.
 - After-pulses

Uniformity-Scans (Sensitivity, Gain, Crosstalk-Maps)

Photon-Detection-Efficiency

PDE Measurement Setup





- Power-ratio R (partial compensation of different sensitivities SiPM/Cal. Sensor)
- XE-Lamp + Monochromator (350-1000nm) Current-measurement (contains crosstalk and after-pulses)

relative PDE

- Pulsed laserdiodes/LEDs (465nm,633nm, 775nm, 870nm) QDC-readout (statistical analysis)
 - PDE without crosstalk and after-pulses

Measurement Principle

PDE without crosstalk and after-pulses

Photons, that arrive at the SiPM are Poisson-distributed:

$$P(n,\lambda) = \frac{\lambda^{n} \cdot e^{-\lambda}}{n!} \Rightarrow P(0,\lambda) = e^{-\lambda}$$
$$\Rightarrow \lambda = N_{pe} = -\ln\left(\frac{N_{Ped.}}{N_{Tot.}}\right)$$

N*_{Ped} is not influenced by optical crosstalk and afterpulses, but needs to be corrected for dark-rate:

$$N_{Ped}^* = N_{ped} - N_{dark}$$



Gain Measurement

• PDE as a function of $U_{over} = U_{bias} - U_{break}$

► Calculate Ubreak (from linear fit results)



Automated Measurement (LABVIEW)

7

- I) Record photoelectron spectrum
- 2) Switch off light and record darkrate spectrum
- 3) Calculate gain and number of photoelectrons
- 4) Apply dark-rate correction \rightarrow PDE
- 5) Set new voltage
- 6) Start over at I

$$PDE = \frac{n_{pe}}{n_{ph}} = \frac{N_{pe} \cdot R/T}{P_{opt}/(h \cdot \frac{c}{\lambda})}$$

 $N_{pe} = Number of Photoelectrons/Pulse$

$$R = Power Ratio$$

$$T = Period \left(30 \cdot 10^{-6} s \right)$$

$$P_{opt} = Optical Power[W]$$

NIST certified photodiode

Example: PDE MPPC 1600pix.



Relative Measurement (350nm-1000nm)



PDE Measurement (Relative)



PDE Curve Scaling

- Curves are scaled to max.
 PDE value at 633nm
- Crosscheck: max. PDE-values at 465nm, 775nm and 870nm are shown.
 - Good agreement
- Measurement at 832nm by factor 5 smaller than other measurements (feature of Laserdiode)
 - Has to be investigated



PDE Curve SensL SPMICRO1020X13

- Scaled to max. PDE value at 633nm.
- Highest PDE at ~500nm
- steep curve below
 500nm



Conclusion

- <u>Setup for SiPM characterization ready for testing</u>
- Basic Characterisation
- Uniformity Scans (sensitivity, gain and crosstalk maps)
- New: PDE-measurement over wide spectral range (350-1000nm)
- Crosstalk and after-pulse measurement (Patrick Eckert)

Further Projects (University of Heidelberg)

- Development of SiPM readout-chip (Wei Shen) (submission planned for summer/early fall)
 - HCAL channel (large dynamical range, low noise)
 - TOF-PET channel (good timing resolution)
- SiPM TDC readout development (Tobias Harion)
 - Further SiPM characterization measurements
 - For PET (in cooperation with DESY)

Backup Slides

³⁵⁰ PDE MPPC³⁰⁰₂₅₀ 600 Pixels

200

70

70.5

- In the case of the MPPC with 1600 pixels the dark-rate correction is small (low dark-rate, short gate 50ns)
- In the following only corrected values are shown



71

71.5

72

72.5

Measurement of Power-ratio R (Ø=0.6mm aperture)



Dark-rate Correction

The pedestal events N^{*}_{Ped.} need to be corrected for the dark-rate. → Acquire dark-rate spectrum at each voltage value. Correction factor:

$$f = \frac{N_{>ped.}^{dark}}{N_{tot}^{dark}} = 1 - \frac{N_{ped}^{dark}}{N_{tot}^{dark}}$$
$$N_{Ped.} = \frac{N_{Ped.}^{*}}{1 - f}$$



PDE (465nm, 633nm, 775nm, 870nm)



PDE was measured at four different wavelengths as a function of U_{over}



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20

SiPM Positioning

- All light should hit the active SiPM-Surface.
- Ø=0.6mm aperture was used for measurements with pulsed laserdiodes.
- Plateau on top allows reproducible positioning at maximum.





Setup for Uniformity-Scans



Crosstalk Map C(x,y)

0^L

MPPC 50µm pitch (400 Pixels)



- Sensitivity Map (statistical analysis of Poisson dist.)
 - ➡ High uniformity
- Current Measurement:
 - Crosstalk-probability higher in the centre (more pixel neighbors)

Crosstalk and Gain Map



*so far only qualitative information about crosstalk possible.